Attorney Docket No. P128-US

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re Application of:

Jonathan Doan

Art Unit: Not Yet Assigned

Serial No.:

Not Yet Assigned

Examiner: Not Yet Assigned

Filed: Herewith

For:

PRE-OXIDIZATION OF DEFORMABLE ELEMENTS OF MICROSTRUCTURES

INFORMATION DISCLOSURE STATEMENT PURSUANT TO 37 CFR 1.97(b)

Commissioner for Patents Alexandria, VA 22313-145

Sir:

The attention of the Patent and Trademark Office is hereby directed to the documents listed on the attached PTO Form 1449. Copies of the cited references are enclosed:

No fee or certification is required in connection with this Information Disclosure Statement, since it is being submitted prior to the last of (1) issuance of a first official action on the merits and (2) expiration of the three month period following filing of the above-captioned application.

The above information is presented so that the Patent and Trademark Office can determine any materiality thereof to the claimed invention. It is respectfully requested that the information be considered during the prosecution of this application and that the cited documents be listed on the front page of any patent issuing from this application.

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The Patent Office is authorized to charge our Deposit Account No. 501516 for any fee which it deems to be required to effect consideration of this statement.

Respectfully submitted,

Gregory R/Muir

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## ATTY. DOCKET NO. SERIAL NO. INFORMATION DISCLOSURE P128-US Not Yet Assigned **CITATION** APPLICANT Jonathan Doan PTO-1449 FILING DATE Herewith GROUP Not Yet Assigned SHEET 1 OF 2 **U.S. PATENT DOCUMENTS CLASS SUBCLASS** FILING DATE **EXAMINER'S** PATENT NO. DATE NAME **INITIALS Published Patent** 09/19/02 Patel, et al. App No.US2002/0132 389 A1 **Published Patent** 09/04/03 Chinn, et al. App No.US2003/0166 342A1 02/20/03 Reid **Published Patent** App No.US2003/0036 215 A1 07/03/03 Miller **Published Patent** No.US2003/0124 462A1 6,396,975B1 05/28/02 Wood, et al. 04/23/02 Martin, et al. 6,376,787,B1 5,709,802 01/20/98 Furuhata, et al. 6,024,801 02/15/00 Wallace, et al. 6,492,309B1 12/10/02 Behr, et al. 5,426,070 06/20/95 Shaw, et al. FOREIGN PATENT DOCUMENTS TRANSLATION **EXAMINER'S** PATENT NO. DATE **COUNTRY** CLASS **SUBCLASS INITIALS** YES NO П OTHER DOCUMENTS (Including Author, Title, Date, Pertinent Pages, Etc.) S. Mubassar Ali, et al., USE OF THERMAL CYCLING TO REDUCE ADHESION OF OTS COATED MEMS CANTILEVERS, 2003, pp. 151-162. Michael R. Houston, et al., SELF-ASSEMBLED MONLAYER FILMS AS DURABLE ANTI-STICTION COATINGS FOR POLYSILICON MICROSTRUCTURES, 1996, pp.42-47. In-Ha Sung, et al., MICRO/NANO-TRIBOLOGICAL CHARACTERISTICS OF SELF-ASSEMBLED MONOLAYER AND ITS APPLICATION IN NANO-STRUCTURE FABRICATION, 2003, pp.808-818 DATE CONSIDERED

EXAMINER: Initial if reference considered, whether or not citation is in conformance with MPEP 609; draw line through citation if not in conformance and not considered. Include copy of this form with next communication to applicant.

**EXAMINER** 

INFORMATION DISCLOSURE CITATION PTO-1449 SHEET 2 OF 2			ATTY. DOCKET NO. P128-US			SERIAL NO. Not Yet Assigned			
			APPLICANT Jonathan Doan						
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	Ţ	U.S. P	ATENT DOCUMENTS	S		T	1		
EXAMINER'S INITIALS	PATENT NO.	DATE	NAME	CL.	ASS	SUBCLASS	FILING DATE		
	6,259,551B1	07/10/01	Jacobs						
	5,936,758	08/10/99	Fisher, et al.						
	5,939,785	08/17/99	Klonis, et al.						
	6,204,085B1	03/20/01	Strumpell, et al.		_				
	5,512,374	04/30/96	Wallace, et al.						
	6,464,892B2	10/15/02	Moon, et al.						
		FOREIG	N PATENT DOCUMENT	TS					
EXAMINER'S INITIALS	PATENT NO.	DATE	COUNTRY	ľ	ASS	SUBCLASS	TRANSLATION		
						YES	NO		
	OTHER DOCU	JMENTS (Inc	luding Author, Title, Date	, Perti	nent ]	Pages, Etc.)			
	Uthara Srinivasan, et al., LUBRICATION OF POLYSILICON MICROMECHANISMS WITH SELF-ASSEMBLED MONOLAYERS, 1998, pp.156-161.								
			LTRICHLOROSILANE-BACTION IN SILICON MICR					LAYER	
	M.P. de Boer et al., ADHESION, ADHESION HYSTERESIS AND FRICTION IN MEMS UNICONTROLLED HUMIDITY AMBIENTS, 1998, pp.127-129.							DER	
·	C. G. Khan Malek, et al., ADHESION PROMOTION BETWEEN POLY(METHYLMETHACRYLATE) AND METALLIC SURFACES FOR LIGA EVALUATED BY SHEAR STRESS MEASUREMENTS, 1998, pp.3543-3546.								
EXAMINER			DATE CONSIDERED						

EXAMINER: Initial if reference considered, whether or not citation is in conformance with MPEP 609; draw line through citation if not in conformance and not considered. Include copy of this form with next communication to applicant.